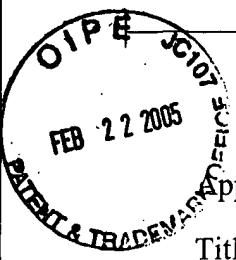


PARSONS HSUE & DE RUNTZ LLP

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94111



Applicant(s): Steve Biellak, et al.

Title: System and Methods for a Wafer Inspection System Using Multiple Angles and Multiple Wavelength Illumination

Application No.: 09/891,693

Filing Date: June 26, 2001

Examiner: Hoa Q. Pham

Group Art Unit: 2877

Docket No.: TNCR.179US0

Conf. No.: 1752

Mail Stop RCE
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Transmitted herewith are the following documents in the above-identified application:

- (1) Return Receipt Postcard;
- (2) Transmittal Letter (1 page - in duplicate);
- (3) Request for Continued Examination (RCE)(1 page);
- (4) Amendment (28 pages);
- (5) Amendment Attachment - Article entitled: "Silicon-On-Insulator Technology"
- (6) Petition For Extension of Time;
- (7) Terminal Disclaimer (2 pages);
- (8) Supplemental Information Disclosure Statement (2 pages);
- (9) PTO Form 1449 (1 sheet)
- (10) 7 Cited References

The fee has been calculated as shown below:

<input checked="" type="checkbox"/> Fee for Terminal Disclaimer	\$	130.00
<input checked="" type="checkbox"/> Fee for Extension of Time		120.00
<input checked="" type="checkbox"/> Fee for RCE		790.00
	Total: \$	<u>1040.00</u>

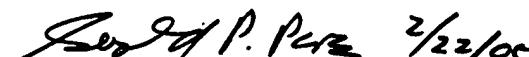
- Conditional Petition for Extension of Time: If an extension of time is required for timely filing of the enclosed document(s) after all papers filed with this transmittal have been considered, an extension of time is hereby requested.
 Please charge all required fees required to our Deposit Account No. 502664.

EXPRESS MAIL NO.:

EV321704785US

February 22, 2005

Respectfully submitted,


Gerald P. Parsons
Reg. No. 24,486
Date
2/22/05